

<b>FORM PTO-1449 (Modified)</b>		US DEPARTMENT OF COMMERCE		Docket No.	Application No.
US Patent and Trademark Office				050623.61	09/997,450
<b>INFORMATION DISCLOSURE CITATION</b> <b>in an Application</b> (Use several sheets if necessary)				Applicant	
				Shamim Malik et al.	
				Filing Date	Group Art Unit
				November 30, 2001	3731

### U.S. PATENT DOCUMENTS

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/RS/	A1	4,486,247	12/4/84	Ecer et al.			
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/RS/	A20	09/997,449	11/30/01	Malik et al.			
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<b>FOREIGN PATENT DOCUMENTS</b>							
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Initial		Number	Publication				Abstract
							Yes No
/RS/	B1	DE 19855786	6/8/00	Germany			X
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<b>OTHER DOCUMENTS</b> (Including Author, Title, Date, Pertinent Pages, etc.)							
/RS/	C1	Malik et al., <i>Development of an Energetic Ion Assisted Mixing and Deposition Process for TIN<sub>x</sub> and Diamondlike Carbon Films, Using a Co-axial Geometry in Plasma Source Ion Implantation</i> , J. Vac. Sci. Technol. A, Vol. 15, No. 6, pp. 2875-2879 (Nov./Dec. 1997).					
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/RS/	C3	Malik et al., <i>Sheath dynamics and dose analysis for planar targets in plasma source ion implantation</i> , Plasma Sources Sci. Technol. Vol. 2, pp. 81-85 (1993).					
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/RS/	C5	Shamim et al., <i>Measurement of electron emission due to energetic ion bombardment in plasma source ion implantation</i> , J. Appl. Phys., Vol. 70, No. 9, pp. 4756-4759 (Nov. 1991).					
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EXAMINER /Ryan Severson/				DATE CONSIDERED 06/27/2008			
EXAMINER: Initial if references considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							